

SYSTEM OF MONITORING ACCUMULATION OF DEPOSITS AND WEAR OF
PLASMA PROCESS KIT PARTS

ABSTRACT OF THE DISCLOSURE

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A go no-go gauge and method for verifying whether a process kit part used within a
plasma chamber of a plasma processing tool has accumulated excessive wear or deposits.

The gauge includes a component for verifying whether a dimension of a process kit part
feature violates a prescribed size tolerance, the violation indicating that the process kit part

10 has accumulated excessive wear or deposits.

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